Docket No.

243938US2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Tohru KOYAMA, et al.

SERIAL NO: NEW APPLICATION

GAU:

FILED:

HEREWITH

EXAMINER:

FOR:

SEMICONDUCTOR DEVICE AND METHOD FOR MACHINING A SEMICONDUCTOR SUBSTRATE

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

Applicant(s) wish to disclose the following information.

REFERENCES

The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed
references are attached, where required, as are either statements of relevancy or any readily available English
translations of pertinent portions of any non-English language references.
A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).
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RELATED CASES

Attached is	a list of appli	cant's pen	ding appl	ication(s) o	r issued patent(s) which may be related	to the present
application.	A copy of the	e patent(s)	, together	with a cop	y of the claims a	and drawings of the per	ding application(s)
is attached	along with PT	O 1449.	_				4
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A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

Each item of information contained in this information disclosure statement was first cited in a commu	
from a foreign patent office in a counterpart foreign application not more than three months prior to the	e filing of
this statement.	

□ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

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C. Irvin McClelland Registration Number 21,124

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(Modified) PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT Tohru KOYAMA, et al. FILING DATE HEREWITH U.S. PATENT DOCUMENTS	N	
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)		
E. YOSHIDA, et al., "High Resolution Laser Voltage Probing", ULSI Development Center, Evaluation & Analysis		
AW Department, Mitsubishi Electric Corporation. (with English Extract)		
S.B. IPPOLITO, et al. "High spatial resolution subsurface microscopy", Applied Physics Letters, The American Ins Physics, Vol. 78, Number 26, June 25, 2001, pp. 4071-4073		
H. TERADA, , "Effectiveness of Solid Immerse Lens", A document from the 14 th Semiconductor Workshop Discount by Hamamatsu Photonics K.K. (with English Extract)	urse hosted	
AZ Additional References sheet(s	s) attached	
Examiner Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	in	